

GAU 1765

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT

(Under 37 CFR 1.97(b) or 1.97(c))

Docket No.
08228/019001

In Re Application Of: Shiro SAKAI et al.

Serial No.
10/044,686

Filing Date
January 11, 2002

Examiner

Group Art Unit

Title: **NITRIDE SEMICONDUCTOR CHIP AND METHOD FOR MANUFACTURING NITRIDE SEMICONDUCTOR CHIP**

Address to:
Assistant Commissioner for Patents
Washington, D.C. 20231

37 CFR 1.97(b)

1. ☒ The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application; within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; or before the mailing date of a first Office Action on the merits, whichever event occurs last.

37 CFR 1.97(c)

2. ☐ The Information Disclosure Statement submitted herewith is being filed after three months of the filing of a national application, or the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; or after the mailing date of a first Office Action on the merits, whichever occurred last but before the mailing date of either:

1. a Final Action under 37 CFR 1.113, or
2. a Notice of Allowance under 37 CFR 1.311,

whichever occurs first.

Also submitted herewith is:

- ☐ a certification as specified in 37 CFR 1.97(e);

OR

- ☐ the fee set forth in 37 CFR 1.17(p) for submission of an Information Disclosure Statement under 37 CFR 1.97(c).

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Payment of Fee

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

- ☐ A check in the amount of _____ is attached.
- ☒ The Assistant Commissioner is hereby authorized to charge and credit Deposit Account No. 50-0591 as described below. A duplicate copy of this sheet is enclosed.
- ☐ Charge the amount of _____
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I certify that this document and fee is being deposited on 6/6/02 with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.

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Tawana L. Garcia

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Dated: 6/6/02

Jonathan P. Osha, Reg. No. 33,986
ROSENTHAL & OSHA L.L.P.
1221 McKinney Street, Suite 2800
Houston, Texas 77010

Telephone: 713-228-8600
Facsimile: 713-228-8778

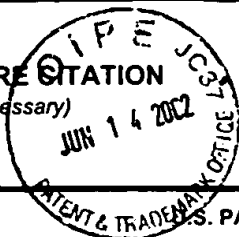
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10/044,686

Shiro SAKAI et al.

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January 11, 2002

GROUP

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U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A1	5,332,697	07/26/1994	Smith et al.	437	242	10/16/1991
	A2	6,090,666	07/18/2000	Ueda et al.	438	257	09/30/1998

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FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	A3	EP 0 942 459 A1	09/15/1999	Europe				
	A4	EP 0 779 666 A2	06/18/1997	Europe				
	A5	11-111867	04/23/1999	Japan				✓

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	A6	Patent Abstracts of Japan, Publication No. 11111867, Publication Date 04/23/1999, 1 page
	A7	"Drastic Reduction of the Dislocation Density in GaN Films by Anti-Surfactant-Mediated Dot Formation"; M. TAKEUCHI et al., Workbook, The Tenth International Conference on Metalorganic Vapor Phase Epitaxy, June 5-9, 2000, Hokkaido University Conference Hall, Sapporo, Japan, 3 pages

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

